

## Optotune tunable optics for Laser processing

Enabling 3D laser processing, beam wobbling and inline inspection

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Dr Branislav Timotijevic, BD Manager
Bernstrasse 388 |CH-8953 Dietikon | Switzerland
Phone +4158856 3000 | www.optotune.com | info@optotune.com

## Optotune provides four core product lines



Laser speckle reducers


Beam shifting devices


Beam steering devices (2D mirrors)


## Optotune products in Laser processing applications

## 2.5 \& 3D laser processing



High precision 2D beam control


Inline inspection and AF


2D mirrors for beam steering


## Products, applications and benefits

## EL-10-42: 3D laser lens

- Laser beam focusing
- High-end laser marking
- Medical lasers


Benefits: large z-range, green and NIR, high repeatability, lifetime, compact, fast

## FMR: Fine steering 2D mirror

- Laser soldering
- Laser beam realignment
- Laser welding / cutting


Benefits: high angular resolution, fast, 2D programmable, small, low weight, customizable

## EL-16-40: Imaging lens

- Laser process inspection (both low and high power)


Benefits: compact, fast, durable, AF, distance measurement, easy to integrate in most camera systems

## Products, applications and benefits

## BSW: Beam shifting window

- Fibre coupling
- Colour cameras
- Hyperspectral imaging


Benefits: 2-axis beam shifting, precise, fast, high transmission, lifetime

## MR: Large angle 2D mirror

- < 1 W 2D beam steering
- Free space communication
- Potential for higher power
(tunable lens not compulsory)


Benefits: large angle, large mirror, compact package, built-in feedback, 1 optical surface for 2 DOF, lifetime

## WIP: EL-7-20 / EL-12-30

- Small dpt range laser processing < 50 W


Benefits: fast, low thermal sensitivity, plano-convex to planoconcave, low power consumption, lifetime

## EL-10-42-OF specs in the NIR and at 532nm

| Product | $\begin{aligned} & \text { EL-10-42-OF-NIR } \\ & \text { EL-10-42-OF-532 } \end{aligned}$ | unit |
| :---: | :---: | :---: |
| Clear aperture | 10 | mm |
| Maximum operating average laser power <br> @ NIR (950-1100 nm) <br> @ 532 nm | $\begin{aligned} & 50 \\ & 20 \end{aligned}$ | W |
| Optical power: tuning range | -2.0 to +2.0 | dpt |
| Optical power: repeatability | typical: < 0.02 |  |
| Optical power: long term stability 8h | 0.04 |  |
| Wavelength range (NIR) | 950-1100 | nm |
| Wavefront error <br> @ 1064 nm <br> @ 532 nm | $\begin{aligned} & <0.15 \\ & <0.3 \end{aligned}$ | $\lambda$ RMS |
| Transmission NIR (950-1100 nm) <br> @ 532 nm | $\begin{aligned} & >94 \% \\ & >95 \% \end{aligned}$ |  |
| Long term radiation damage @ 1064 nm: $40 \mathrm{~mJ} / \mathrm{cm} 2$ at 20 kHz | No effect after 2000 h |  |
| Damage threshold @ 1064 nm : 125 ns -pulsed at 50 kHz 10 ps -pulsed at 50 kHz | $\begin{gathered} 2.6 \\ 2.05 \end{gathered}$ | $\mathrm{J} / \mathrm{cm}^{2}$ |
| Response time with EL-E-OF-A analog board | $\begin{aligned} & \text { 80\% step: } 12 \\ & \text { 20\% step: } 6 \end{aligned}$ | ms |
| Response time with Scaps digital board | 80\% step: 8 <br> 20\% step: 4.5 | ms |
| Focal length resolution | Continuous (depends on control electronics) |  |
| Lifecycles (10\%-90\% sinusoidal) | $>1^{\prime} 000{ }^{\prime} 000{ }^{\prime} 000$ |  |

Typical parameters in a marking system with $f=160 \mathrm{~mm}$ f-theta lens

| Max z-tuning range | 100 | mm |
| :--- | :---: | :---: |
| Repeatability $(10 \%-90 \% \text { step })^{*}$ | typical $:<500$ | $\mu \mathrm{~m}$ |
| Long term drift over $8 \mathrm{~h}^{*}$ | max: $<1000$ |  |



All EL-10-42-OF lenses undergo extensive OQC tests including laser testing

## Analog and digital drivers for EL-10-42-OF

|  | EL-E-OF-A (2.5D) | SCAPS Optotune-DSD-2-0 (3D) |
| :---: | :---: | :---: |
|  |  | XY2-100 integration by USB calibration interface Only one power supply <br> Thermal Control and lens status signal |
| Interface | Analog 0-5V | Digital XY2-100, X-Y bi-directional Scaps interface |
| Controller | Microprocessor based | FPGA based |
| Intelligence | Standard PID control | Model based drive algorithm |
| 80\% step response | 12 ms | 8 ms |
| Demonstrated processing speed on 45deg slope ( 160 mm F-Theta) | $0.7 \mathrm{~m} / \mathrm{s}$ | 6m/s |
| Suitable operation | Z-Stepping for 2D processing | True 3D processing |

### 2.5D and 3D laser processing with EL-10-42-OF

### 2.5D Z-stepping



## 3D laser focus control



## Benefits:

- Compact
- Long lifetime
- High z-speed
- Constant spot
- LAM


## Low-power laser applications with MR mirrors



## Benefits:

- Large angle
- Small footprint
- Single optical surface


## Applications:

- Laser templating
- Free space communication
- Low-power beam steering

MR-15-30 (quasi-static)


| MR-10-30 (resonant) |  |
| :--- | :--- |
| Mirror size | 10 mm |
| Mechanical tilt - fast axis (half angle) | $12.5^{\circ}$ |
| Full-scale bandwidth - fast axis | 280 Hz |
| Mechanical tilt - slow axis (half angle) | $25^{\circ}$ |
| Full-scale bandwidth - slow axis | 20 Hz |
| Mech. Repeatability RMS typical | $30-100 \mathrm{\mu rad}$ <br> (slow axis) |
| Footprint | $30 \times 14.5$ |
| Position feedback | yes |
| Laser power | up to 1 W |

## High-power, fine laser steering with FMR mirrors

## Benefits



- Compact
- Long lifetime
- Fast
- Precise
- Programmable pattern


## Applications:

- Laser cutting and welding
- Laser soldering, cleaning and ablation
- Laser cavity alignment (Q-switching)
- Point and shoot / raster (lissajous) scanning


| FMR-20 |  |
| :--- | :--- |
| Mirror size | $20 \times 20 \mathrm{~mm}$ |
| Mechanical tilt angle (p-p) | $0.4^{\circ}$ |
| Motion pattern | 2D programmable |
| Bandwidth | 250 Hz @ $0.2^{\circ} \mathrm{p}-\mathrm{p}$ |
| Mirror coating | Au, dielectric, custom |
| Laser wavelength | UV, VIS, NIR, IR |
| Laser power | Several kW* |
| Position feedback | Open loop |
| External sensor for feedback | Can be added |
| Power consumption | $<4 W$ |
| Size (width $\times$ height $\times$ depth | $47 \times 35 \times 3.65 \mathrm{~mm}$ |
| Weight | 9 g |

## Inline inspection with Distance measurement using EL-16-40




Depth from focus: A focus tunable lens in conjunction with an autofocus algorithm can reliably measure distance to an arbitrary object in less than a second

## Inline inspection up to 50W using EL-10-42-OF



